

Agilent Nano Indenter G300

Data Sheet



Figure 1. Top: close-up of XP indenter head.
Middle: the Nano Indenter G300.
Bottom: G300 vacuum chuck stages.

Features and Benefits

- Newly integrated tool simplifies determination of indenter area function and load-frame stiffness
- Accurate, repeatable results compliant with ISO 14577 standard
- Large sample stage supports test specimens with diameters up to 300 mm
- Full testing automation enables nanoindentation instrument to run unattended
- Electromagnetic actuation allows unparalleled dynamic range in force and displacement
- Flexible, upgradeable instrument can be configured for repeatable specific applications or a variety of new applications
- Dynamic properties characterization via continuous measurement of stiffness by indentation depth
- Outstanding software with real-time experimental control, easy test protocol development, and precision drift compensation

Applications

- Semiconductor, thin films, MEMs (wafer applications)
- Hard coatings, DLC films
- Composite materials, fibers, polymers
- Metals, ceramics
- Biomaterials, biology

Overview

The Agilent Nano Indenter G300 utilizes a large sample stage that supports test specimens with diameters up to 300 mm. An excellent investment for industrial users, this versatile nanoindentation instrument provides a fast, reliable method to acquire mechanical data on uncut silicon wafers. The G300 permits testing of multiple layers, facilitating product development and failure analysis, while keeping wafers intact for further tests.

Electromagnetic actuation allows the Nano Indenter G300 to achieve unparalleled dynamic range in force and displacement. The G300 enables measurement of Young's modulus and hardness in compliance with ISO 14577. It also enables measurement of deformation over six orders of magnitude (from nanometers to millimeters). Mechanical properties at this scale such as hardness, modulus of elasticity, and fracture behavior can have a significant effect on yield, performance, and longevity of semiconductor devices.

A variety of options can be added to the Nano Indenter G300 to accommodate testing needs such as frequency-specific testing, quantitative scratch and wear testing, integrated probe-based imaging, expanded load capacity up to 10 N, and customizable test protocols.

With the Nano Indenter G300, users are able to quantify the relationship between structure, properties, and performance of their materials quickly and easily with minimal



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sample preparation. The user-friendly design of the G300 simplifies training requirements — standard tests can be run on the same day the instrument is installed. Every G300 is backed by highly responsive Agilent Technologies customer service personnel.

Knowledgeable and experienced regional applications engineers are available to guide users through more advanced testing, provide outstanding technical support, and offer unmatched applications expertise.

Advanced Design

All nanoindentation experiments rely on the accuracy of the fundamental load and the displacement data, requiring the highest precision control of load applied to the sample. The Nano Indenter G300 is powered by electromagnetic actuation-based force transducers to ensure precise measurements; users can program experiments with each force transducer and switch between them at any time. The instrument's unique design avoids lateral displacement artifacts, while software compensates fully for any drift in force.

The Nano Indenter G300 is software controlled and simple to use. Operators need only decide where to place the indentations and what experiments to perform at those positions. Full testing automation enables the instrument to run unattended and report results in both Microsoft® Word and Excel. The G300 can help streamline materials selection processes and large-scale industrial testing.

The G300 includes a motorized sample manipulation table with mouse control, a vibration isolation table and environmental enclosure, an optical imaging system, a video camera with frame-grabbing software, and a pre-mounted diamond indentation tip. The G300 also includes a software-controlled, automated handset as well as a fully automated data acquisition and control system with PC, monitor, keyboard, color inkjet printer, and Agilent NanoSuite 6.1 Professional software.

New Enhanced Dynamic Contact Module II Option

The Nano Indenter G300 standard configuration utilizes the Agilent XP indentation head, which delivers <0.01 nm displacement resolution and >500 µm maximum indentation depth. To extend the range of load-displacement experimentation to the surface contact level, the G300 can be equipped with the new Agilent Dynamic Contact Module II (DCM II) option. This option offers all of the impressive performance afforded by Agilent's original DCM option as well as several new advantages, including 3x higher loading capability (30 mN max load), easy tip exchange for quick removal and installation of application-specific tips, and a full 70 µm range of indenter travel.

With the DCM II option, researchers can study not only the first few nanometers of an indentation into the surface of a material, but even the pre-contact mechanics. At this scale, the noise level of the indentation system also must be optimized to enhance its actual displacement measurement capability. Using standard methods, the displacement resolution of the DCM II is determined to be 0.0002 nm (0.2 picometers). Even more importantly, real-world testing shows that the noise levels are typically less than an angstrom, ensuring the best resolution of any indenter on the market today. The DCM II has the lowest noise floor of any instrument of its type.

Continuous Stiffness Measurement (CSM) Option

In conventional quasi-static indentation testing, the stiffness of contact is determined by analyzing the force vs. displacement curve during unloading. This depth-sensing method provides a single measurement for the given indentation depth. The Agilent Continuous Stiffness Measurement (CSM) technique, which is compatible with both the XP and the DCM II indentation heads, satisfies application requirements that must take into account dynamic effects, such as strain rate and frequency.

With the CSM option, the Nano Indenter G300 applies a load to the indenter tip to force the tip into the surface while simultaneously superimposing an oscillating force with a force amplitude generally several orders of magnitude smaller than the nominal load. The CSM option offers a means of separating the in-phase and out-of-phase components of the load-displacement history. This separation provides an accurate measurement of the location of initial surface contact and continuous measurement of contact stiffness as a function of depth or frequency, thus eliminating the need for unloading cycles. Since the contact stiffness is determined directly, no assumptions (such as mechanical equilibrium) are required to correct for elasticity.

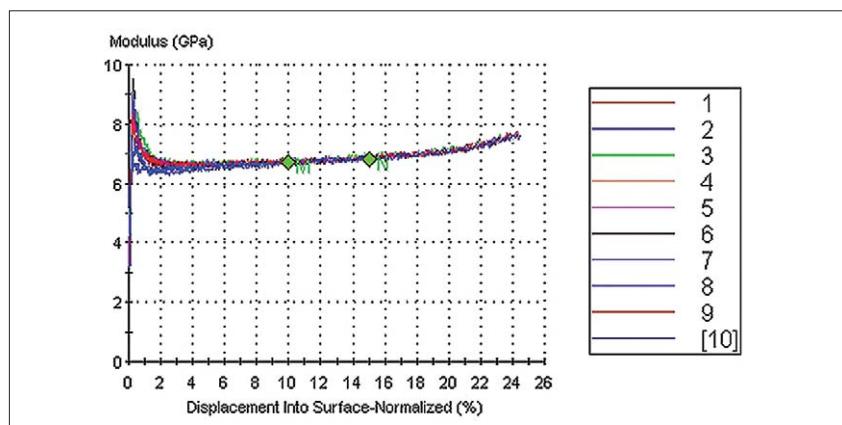


Figure 2. Low-k film normalized by percent of film thickness. Non-destructive testing was done at predetermined sites using a method that allows collection of substrate-independent properties of your film.

This makes CSM a powerful tool not only for stiff materials such as metals, alloys, and ceramics but also for time-dependent materials like polymers, structural composites, and biomedical materials.

The state-of-the-art CSM option provides the only means available to both fully characterize dynamic properties in the nanometer range and accurately characterize viscoelastic materials providing values such as storage modulus. Indentation tests using CSM can be controlled with a constant strain rate, a critical test parameter for material systems such as pure metals or low-melting-point alloys, and polymer films and film/substrate systems. This level of control is not possible with the conventional method.

Lateral Force Measurement (LFM) Option

There are several additional performance-extending Nano Indenter G300 options available for use with the standard XP indentation head. The Agilent Lateral Force Measurement (LFM) option provides three-dimensional quantitative analysis for scratch testing, wear testing, and MEMS probing. This option enables force detection in the X and Y directions to examine shear forces. Tribological studies benefit greatly from the LFM option for determination of the critical load and coefficient of friction over the scratch length.

High Load Option

The capabilities of the Nano Indenter G300 can also be enhanced via the Agilent High Load option. Designed for use with the standard XP indentation head, this option expands the load capabilities of the Nano Indenter G300 up to 10 N of force, allowing the complete mechanical characterization

of ceramics, bulk metals, and composites. The High Load option has been engineered to avoid sacrificing the instrument's load and displacement resolutions at low forces while seamlessly engaging at the point in the test protocol when extra force is required.

New Enhanced NanoSuite 6.1 Professional Software

Every Nano Indenter G300 comes with Agilent NanoSuite 6.1 Professional software, a premium-performance package that gives researchers in scientific and industrial settings an unprecedented combination of speed, flexibility, and ease of use. NanoSuite 6.1 offers a variety of brand new, prewritten test methods, including an exclusive nanoindentation technique for making substrate-independent measurements of thin film materials, several novel techniques for testing polymers, and improved scratch test methods. Agilent's field-proven method for testing in compliance with ISO 14577, the international standard for indentation testing, is provided as well.

NanoSuite 6.1 even includes a fully integrated tool that greatly simplifies the determination of indenter area function and load-frame stiffness. Once a rather involved and time-consuming endeavor, this process now requires only a couple of mouse-clicks within the NanoSuite 6.1 program. Prewritten methods for testing gels (DCM II indentation head and CSM option required) and for measuring strain-rate sensitivity (XP indentation head and CSM option required) have also been added to NanoSuite 6.1.

Additional new capabilities allow a standard batch of tests comprising 25 or more samples to be set up in 5 minutes or less, 2D graphs to be plotted on-screen and exported directly to

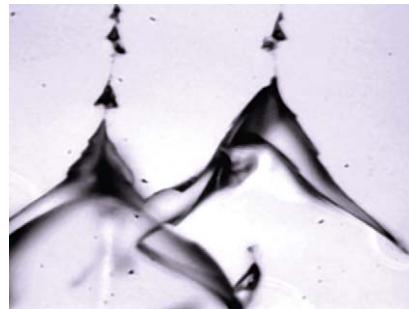


Figure 3. The G300 tests for the adhesion of film. This image shows the delamination of a polymer film on glass.

Microsoft Excel while preserving all labels and scales, and sample files to be organized by project and subproject. NanoSuite 6.1 also provides Microsoft Windows 7 (32-bit) compliance for current systems and a convenient PDF printer to replace hardware printers.

As in the package's previous iteration, an intuitive interface allows users to set up and run experiments quickly — changing test parameters as often as desired — with just a few clicks. NanoSuite 6.1 offers support of small force/displacement measurements, surface topology, stiffness mapping, scratch tests, and more. Versatile imaging capabilities, a survey scanning option, and streamlined test method development help researchers get from testing to results in record time.

NanoVision Software Option

The Agilent NanoVision option for the Nano Indenter G300 is used to probe the surface of a sample, generating a 3D map of the surface. Backed by decades of nanomechanical testing experience, the NanoVision nanomechanical microscopy option delivers quantitative imaging by coupling a linear electromagnetic actuation-based indentation head with a closed-loop nanopositioning stage. NanoVision allows users to create quantitative high-resolution images using a Nano Indenter G300, target indentation test sites with nanometer-scale precision, and examine residual impressions in order to quantify material response phenomena such as pile-up, deformed volume, and fracture toughness. This option also lets users target and characterize individual phases of complex materials.

Nanoindentation instruments from Agilent Technologies conform to the ISO 14577 standard, delivering confidence in test accuracy and repeatability. These state-of-the-art solutions ensure reliable, high-precision measurement of nanomechanical properties for research and industry.

Agilent Nano Indenter G300 Specifications

Standard XP Indentation Head

Displacement resolution	<0.01 nm
Total indenter travel	2 mm
Maximum indentation depth	>500 µm
Load application	Coil / magnet assembly
Displacement measurement	Capacitance gauge
Loading capability	
Maximum load (standard)	500 mN
Maximum load with DCM II option	30 mN
Maximum load with High Load option	10 N
Load resolution	50 nN
Contact force	<1.0 µN
Load frame stiffness	$\sim 5 \times 10^6$ N/m
Indentation placement	
Useable surface area	225 mm x 300 mm
Position control	Automated remote with mouse
Positioning accuracy	1 µm
Microscope	
Video screen	25x (x objective mag.)
Objective	10x and 40x

DCM II Indentation Head Option

Displacement resolution	0.0002 nm (0.2 picometers)
Range of indenter travel	70 µm
Loading column mass	<150 mg
Load application	Coil / magnet assembly
Displacement measurement	Capacitance gauge
Typical leaf spring stiffness	~100 N/m
Typical damping coefficient	0.02 Ns/m
Typical resonant frequency	120 Hz
Lateral stiffness	80,000 N/m
Loading capability	
Maximum load	30 mN (13 gm)
Load resolution	3 nN (0.3 µgm)

LFM Option

Maximum lateral force	>250 mN
Lateral resolution	<2 µN
Maximum scratch distance	>100 mm
Scratch speed	100 nm/s up to 2 mm/s

High Load Option

Maximum force	10 N
Load resolution	≤1 mN
Maximum indentation depth	≥500 µm
Displacement resolution	0.01 nm
Frame stiffness	$\geq 5 \times 10^6$ N/m

NanoVision Option

X-Y scan range	100 µm x 100 µm
Z scan range	Indentation head dependent
Positioning accuracy	≤2 nm
Resonant frequency	>120 Hz

Nano Mechanical Systems from Agilent Technologies

Agilent Technologies, the premier measurement company, offers high-precision, modular nano-measurement solutions for research, industry, and education. Exceptional worldwide support is provided by experienced application scientists and technical service personnel. Agilent's leading-edge R&D laboratories ensure the continued, timely introduction and optimization of innovative, easy-to-use nanomechanical system technologies.

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